IN THE SPECIFICATION:

Please amend the specification as follows:

Please add the following paragraph between paragraph [0021-A] and [0022]:

[0021-B] FIG. 12A is a schematic view showing the Digital Micro-mirror Device (DMD) with the array of inclinable mirrors, and FIG 12B is a schematic cross-sectional view showing the inclinable mirror can be operated at on-state, off-state and flat-state.

Please amend the paragraph [0028] as follows:

[0028] FIG. 8 shows the relative positions of the on-state, off-state, and flat state of the light beam at the stop of the projection lens 82. Please refer to FIG 12A, the Digital Micro-mirror Device (DMD) 100 has the array of inclinable mirrors 102, and each mirror 102, as shown in FIG 12B, can be operated at on-state 104a, off-state 104b, or flat-state 104c, to reflect the incident light beam 73 for generating the on-state light beam 61, the flat-state light beam 62, or the off-state light beam 63. The solid line respectively represents the on-state light beam 61, flat state light beam 62, and off-state light beam 63 of the prior art, and the dotted line respectively represents the on-state light beam 64, flat-state light beam 65, and off-state light beam 66 of the present invention. In theory, the bigger the on-state light beam 61 is, the more light flux can be allowed to enter into the stop for achieving better brightness. If the on-state light beam 61 is enlarged to produce a light spot 611 having the same size as the stop 67, the flat-state light beam 62 and off-state light beam 63 will also be enlarged as light spot 68 and 69 respectively. That causes the some overlaps between light spot 611 and light spot 68 to decrease the projection contrast. Therefore, the on-state light beam 61, flat state light beam 62, and off-state light beam 63 of the prior art are set to be next to each other and have no X-axial overlap between them, so that the maximum light flux can be allowed to pass without the sacrifice of contrast to achieve the best balance.